

DOCKET NO: 263788US2PCT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :
KEISUKE KAWAMURA, ET AL. : EXAMINER: ARANCIBIA, M. G.
SERIAL NO: 10/519,475 :
FILED: DECEMBER 28, 2004 : GROUP ART UNIT: 1763
FOR: APPARATUS FOR PLASMA :
PROCESSING, METHOD OF
PROCESSING SUBSTRATE
THEREWITH, APPARATUS FOR
PLASMA-ENHANCED CHEMICAL
VAPOR DEPOSITION, AND METHOD
FOR FILM FORMATION THEREWITH

ELECTION

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

In response to the election requirement dated April 9, 2007, Applicants elect Species A, identified in the outstanding Official Action as corresponding to Figure 1, for further examination on the merits. Applicants identify Claims 1-7, 10, and 11 as readable on the elected species. Applicants reserve the right to file one or more divisional applications directed to the non-elected species.

Accordingly, examination on the merits of Claims 1-7, 10, and 11 is believed to be in order and an early and favorable action is respectfully requested.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



Gregory J. Maier
Attorney of Record
Registration No. 25,599

Customer Number
22850

Tel: (703) 413-3000
Fax: (703) 413 -2220
(OSMMN 06/04)

Remus F. Fetea, Ph.D.
Registration No. 59,140

I:\ATTY\REF\26s\263788\263788 ELECTION.DOC